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520.34403CV4

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): T. MASUDA, et al
Serial No.: 09/421,043
Filed: October 20, 1999
For: PLASMA ETCHING APPARATUS AND PLASMA ETCHING METHOD
Group: 1763
Examiner: A. Mulero

SUPPLEMENTAL AMENDMENT

Mail Stop: AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

February 13, 2006

Sir:

The following amendments and remarks are respectfully submitted in connection with the RCE of the above-identified application in response to the Office Action dated July 26, 2005 and as a supplemental to the Amendment filed December 27, 2005 in light of the Office Communication dated January 12, 2006.

Amendment of the Claims; and

Remarks are included following the amendments.